

23 September 2004

Updated Search

09/836,844

| L Number | Hits | Search Text | DB | Time stamp |
|----------|------|-----------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------|---------------------------------------------|---------------------|
| - | 4 | 6214193.pn. 6099702.pn. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 11:32 |
| - | 2 | 3950184.pn. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 11:58 |
| - | 14 | 3950184.URPN. | USPAT | 2003/04/25 11:58 |
| - | 5 | ("3141793" "3656173" "3950184" "4451507" "5084483").PN. | USPAT | 2003/04/25 12:01 |
| - | 17 | ("3798056" "3950184" "4339319" "4373988" "4466864" "4856456" "5000827" "5169408" "5312487" "5340437" "5472592" "5670034" "5677000" "5893966" "5930549" "6077412" "6099702").PN. | USPAT | 2003/04/25 13:58 |
| - | 33 | 5000827.URPN. | USPAT | 2003/04/25 12:04 |
| - | 53 | 5169408.URPN. | USPAT | 2003/04/25 12:41 |
| - | 33 | 5000827.URPN. | USPAT | 2003/04/25 12:50 |
| - | 2247 | 204/212,225,237,275.1.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 13:58 |
| - | 773 | 204/224r.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 13:58 |
| - | 2837 | 204/212,225,237,275.1.ccls. 204/224r.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:00 |
| - | 2190 | 118/416,500,501.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:01 |
| - | 5015 | (204/212,225,237,275.1.ccls. 204/224r.ccls.) 118/416,500,501.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:01 |
| - | 1027 | ((204/212,225,237,275.1.ccls. 204/224r.ccls.) 118/416,500,501.ccls.) and (semiconductor or wafer) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:02 |
| - | 557 | ((((204/212,225,237,275.1.ccls. 204/224r.ccls.) 118/416,500,501.ccls.) and (semiconductor or wafer)) and (spinning or spin or spun or rotate or rotated or rotating) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:02 |

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| - | 90 | (((204/212,225,237,275.1.ccls. 204/224r.ccls.) 118/416,500,501.ccls.) and (semiconductor or wafer)) and (spinning or spin or spun or rotate or rotated or rotating)) and (recycle or recycling or recycler or reclaim or reclamation or recycled or reclaimed or recover or recovered or recovery or recovering) ("5922138" "6168691" "6187152").PN. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:36 |
| - | 3 | | USPAT | 2003/04/25 14:29 |
| - | 0 | 6352623.URPN. | USPAT | 2003/04/25 14:33 |
| - | 3776 | 205/122,123,157,220.ccls. 427/98,299,352.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:34 |
| - | 940 | (205/122,123,157,220.ccls. 427/98,299,352.ccls.) and (semiconductor or wafer) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:34 |
| - | 504 | ((205/122,123,157,220.ccls. 427/98,299,352.ccls.) and (semiconductor or wafer)) and (cleaning or clean or cleaned or rinsed or rinse or rinsing or wash or washing or washed) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:35 |
| - | 53 | (((205/122,123,157,220.ccls. 427/98,299,352.ccls.) and (semiconductor or wafer)) and (cleaning or clean or cleaned or rinsed or rinse or rinsing or wash or washing or washed)) and (recycle or recycling or recycler or reclaim or reclamation or recycled or reclaimed or recover or recovered or recovery or recovering) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:36 |
| - | 90 | (((204/212,225,237,275.1.ccls. 204/224r.ccls.) 118/416,500,501.ccls.) and (semiconductor or wafer)) and (spinning or spin or spun or rotate or rotated or rotating)) and (recycle or recycling or recycler or reclaim or reclamation or recycled or reclaimed or recover or recovered or recovery or recovering) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 15:01 |
| - | 53 | (((205/122,123,157,220.ccls. 427/98,299,352.ccls.) and (semiconductor or wafer)) and (cleaning or clean or cleaned or rinsed or rinse or rinsing or wash or washing or washed)) and (recycle or recycling or recycler or reclaim or reclamation or recycled or reclaimed or recover or recovered or recovery or recovering) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:37 |
| - | 225 | (((205/122,123,157,220.ccls. 427/98,299,352.ccls.) and (semiconductor or wafer)) and (cleaning or clean or cleaned or rinsed or rinse or rinsing or wash or washing or washed)) and (spin or spinning or spun or rotate or rotating or rotated or revolve or revolved or revolving) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2003/04/25 14:37 |

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| - | 811 | 204/224r.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/08 09:18 |
| - | 2957 | 204/212,225,237,275.1.ccls. 204/224r.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/08 09:18 |
| - | 373 | (204/212,225,237,275.1.ccls. 204/224r.ccls.) and (wafer or semiconductor or microelectronic) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/08 09:19 |
| - | 8 | ((204/212,225,237,275.1.ccls. 204/224r.ccls.) and (wafer or semiconductor or microelectronic)) and (tilt\$5 and spray\$5) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/08 09:19 |
| - | 14 | ((204/212,225,237,275.1.ccls. 204/224r.ccls.) and (wafer or semiconductor or microelectronic)) and (tilt\$5 and (spray\$5 or nozzle)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/08 10:12 |
| - | 100 | (204/198-227.ccls. and (microelectronic or wafer or semiconductor)) and ((contact or electrode or cathode) with (clean\$3 or wash\$3 or rins\$5)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/08 11:48 |
| - | 2 | 6156167.pn. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/08 11:48 |
| - | 1 | 836844.apn. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/01/09 09:24 |
| - | 438 | 204/198-227.ccls. and (microelectronic or wafer or semiconductor) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/09 09:53 |
| - | 20 | (204/198-227.ccls. and (microelectronic or wafer or semiconductor)) and (tilt\$4 with (wafer or substrate or semiconductor or microelectronic)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/09 09:53 |
| - | 5 | 6613214.pn. 6258220.pn. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/09 09:44 |
| - | 3 | 6251236.pn. 6258220.pn. | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/09 09:44 |
| - | 11422 | (205/\$.ccls. or 204/\$.ccls.) and (microelectronic or wafer or semiconductor) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/09 09:53 |

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|---|-------|-----------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------|---------------------------------------------------------|---------------------|
| - | 121 | ((205/\$.ccls. or 204/\$.ccls.) and (microelectronic or wafer or semiconductor)) and (tilt\$4 with (wafer or substrate or semiconductor or microelectronic)) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/09 09:54 |
| - | 101 | ((((205/\$.ccls. or 204/\$.ccls.) and (microelectronic or wafer or semiconductor)) and (tilt\$4 with (wafer or substrate or semiconductor or microelectronic))) not ((204/198-227.ccls. and (microelectronic or wafer or semiconductor)) and (tilt\$4 with (wafer or substrate or semiconductor or microelectronic))) | USPAT; US-PGPUB; EPO; JPO; DERWENT | 2004/01/09 09:54 |
| - | 1554 | 422/292,300.ccls. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:54 |
| - | 16 | 422/292,300.ccls. and (wafer or microelectronic) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:54 |
| - | 21646 | (clean\$3 or rins\$3) near3 (wafer or microelectronic) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:55 |
| - | 21418 | (clean\$3 or rins\$3) near3 (wafer or microelectronic) and (spray or stream)nic | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:55 |
| - | 4282 | ((clean\$3 or rins\$3) near3 (wafer or microelectronic)) and (spray or stream) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:55 |
| - | 3472 | ((((clean\$3 or rins\$3) near3 (wafer or microelectronic)) and (spray or stream)) and (chemical or fluid)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:55 |
| - | 2269 | (((((clean\$3 or rins\$3) near3 (wafer or microelectronic)) and (spray or stream)) and (chemical or fluid)) and (chamber or container)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:56 |
| - | 4644 | 134/\$.ccls. and (wafer or microelectronic) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:56 |

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|---|-----|-------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------|---------------------------------------------------------|---------------------|
| - | 452 | 134/58r,94.1,95.1,95.2,95.3,103.2,198.ccls. and (wafer or microelectronic) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:56 |
| - | 320 | (134/58r,94.1,95.1,95.2,95.3,103.2,198.ccls. and (wafer or microelectronic)) and (clean\$3 or rins\$3) near3 (wafer or microelectronic) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:56 |
| - | 196 | ((134/58r,94.1,95.1,95.2,95.3,103.2,198.ccls. and (wafer or microelectronic)) and (clean\$3 or rins\$3) near3 (wafer or microelectronic)) and (spray or stream) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:57 |
| - | 132 | (((((134/58r,94.1,95.1,95.2,95.3,103.2,198.ccls. and (wafer or microelectronic)) and (clean\$3 or rins\$3) near3 (wafer or microelectronic)) and (spray or stream)) and (chemical or fluid)) and (chamber or container)) and (rais\$3 or lower\$3 or vertical\$4) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:57 |
| - | 2 | 6050275.pn. | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/09/23 10:57 |